

Form PTO-1449		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE			ATTY. DOCKET NO. MI22-1904	PRIORITY SERIAL NO. 09/843,116	
LIST OF ART CITED BY APPLICANT (Use several sheets if necessary)					APPLICANT Michael Nutall et al.		
					PRIORITY FILING DATE April 24, 2001		PRIORITY GROUP 2813
U.S. PATENT DOCUMENTS							
*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA	4,497,683	02/1985	Celler et al.	156	603	
	AB	4,963,506	10/1990	Liaw et al.	438	482	
	AC	5,080,933	01/1992	Grupen-Semansky et al.	427	255.1	
	AD	5,110,757	05/1992	Arst et al.	438	489	
	AE	5,124,276	06/1992	Samata et al.	438	607	
	AF	5,364,815	11/1994	Osada	438	489	
	AG	5,441,012	08/1995	Aketagawa et al.	117	86	
	AH	5,006,911	04/1991	Sivan	357	23.11	
	AI	5,818,100	10/1998	Grider et al.	257	616	
	AJ	5,037,775	08/1991	Reisman	437	89	
	AK	5,646,073	07/1997	Grider et al.	437	233	
FOREIGN PATENT DOCUMENTS							
		Document Number	Date	Country	Class	Subclass	Translation
	AL						Yes
	AM						No
	AN						
	AO						
	AP						
OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)							
	AR			Violette, Katherine E., et al., "Low Temperature Selective Silicon Epitaxy by Ultra High Vacuum Rapid Thermal Chemical Vapor Deposition Using Si ₂ H ₆ , H ₂ and Cl ₂ ", Appl. Phys. Lett., Vol. 68(1), pp. 66-68 (January 1996).			
	AS			Wolf, Stanley, et al. "Chemical Vapor Deposition of Amorphous and Polycrystalline Films, Silicon Processing for the VLSI Era", Vol. 1: Process Technology, pp. 183 and 191 (Lattice Press).			
	AT			<i>References can't be found in the parent case, 09/843,116. Applicant needed to provide these references.</i>			
EXAMINED				DATE CONSIDERED			

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*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate	
	AA	6,013,575	01/2000	Itoh	438	641		
	AB	4,948,755	08/1990	Mo	437	195		
	AC	4,966,868	10/1990	Murali et al.	437	193		
	AD	5,607,878	03/1997	Otsuka et al.	437	187		
	AE	5,663,098	09/1997	Creighton et al.	438	675		
	AF	6,017,823	01/2000	Shishiguchi et al.	438	696		
	AG	6,069,036	05/2000	Kim	438	238		
	AH	5,798,278	08/1998	Chan et al.	437	43		
	AI	5,037,778	08/06/91	Reisman	437	89		
	AJ							
	AK							
FOREIGN PATENT DOCUMENTS								
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Form PTO-1449	U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE	ATTY. DOCKET NO. MI22-1904	SERIAL NO. 10/050,426
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		FILING DATE January 15, 2002	GROUP 2813



U.S. PATENT DOCUMENTS

*Examiner's Initials		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
	AA						
	AB						
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FOREIGN PATENT DOCUMENTS

		Document Number	Date	Country	Class	Subclass	Translation	
							Yes	No
	AJ							
	AK							
	AL							

OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

	AM	Wolf, Stanley, "Silicon Processing for the VLSI Era", Vol. 2: Process Integration, pg. 45 (Lattice Press)						
	AN							
	AO							

EXAMINER *Sarkar* DATE CONSIDERED

7/10/03

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U.S. PATENT & TRADEMARK DOCUMENTS

*Examiner Initial		Document Number	Date	Name	Class	Subclass	Filing Date If Appropriate
<i>m</i>	AA	5,118,639	06/1992	Roth et al.	437/	41	_____
	AB						
	AC						
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	AH						
	AI						
	AJ						
	AK						
	AL						

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OTHER REFERENCES (including Author, Title, Date, Pertinent Pages, Etc.)

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